

Abstract of the Disclosure

An organic thin film manufacturing method and manufacturing apparatus is disclosed in which control of the heating method of the organic material can be carried out simply, temperature control of the organic material to be subjected to vapor deposition is easy, and the reproducibility and stability of the film thickness of the organic thin film obtained are excellent. According to the organic thin film manufacturing method an organic material is fed in a vapor state into a vapor deposition apparatus positioned in a vacuum chamber from a material introducing part positioned outside the vapor deposition apparatus to form a thin film of the organic material on at least one substrate disposed inside the vapor deposition apparatus. The material introducing part has a structure such that the pressure inside can be set independently of that inside the vapor deposition apparatus, and it also has an exhaustor independent to that of the vapor deposition apparatus.